

Notice of References Cited	Application/Control No. 10/015,757	Applicant(s)/Patent Under Reexamination KIM, HYUNG-JUN	
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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-3,838,984	10-1974	Crane et al.	29/193.5
	B	US-5,042,147	08-1991	Tashiro	29/847
	C	US-5,067,006	11-1991	Shiga	357/74
	D	US-5,404,045	04-1995	Mizushima	257/698
	E	US-5,612,514	03-1997	Lam	174/261
	F	US-5,861,667	01-1999	Kuwano	257/691
	G	US-5,926,733	07-1999	Heo	438/622
	H	US-6,031,281	02-2000	Kang et al.	257/692
	I	US-6,064,116	05-2000	Akram	257/723
	J	US-2001/0002065	05-2001	Drehobl et al.	257/678
	K	US-6,268,644	07-2001	Umehara et al.	257/667
	L	US-2002/0024149	02-2002	Nakamura	257/786
	M	US-2002/0079596	06-2002	Terauchi	257/908

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	411214522	08-1999	Japan	Murai et al.	H01L021/82
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Fontana et al., Corrosion Engineering, 1978, McGraw-Hill, 2d ed, 169-170).
	V	Kim et al., Investigation of Aluminum CMP to Apply to Sub-Quarter Micron DRAM devices, 2000, Proceedings of 5 th CMP-MIC, 471-476.
	W	Lin et al., Pitting and Copper Accumulation Associated with Aluminum CMP, 16 th International VLSI Multilevel Interconnection Conference, 132-137.
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,414,387	07-2002	Hara et al.	257/691
	B	US-2002/0163068	11-2002	Asada	257/690
	C	US-5,322,764	06-1994	Kamiyama et al.	430/324
	D	US-5,534,728	07-1996	Kim et al.	257/692
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

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	N					
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	T					

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